

Korea-Switzerland Joint Seminar

1. Title of Seminar:

The Second Korea-Switzerland Joint Symposium on New Materials and Process Issues in MEMS Technology

2. Period and Place:

June 15 ~ June 20, 2001, EPFL, Lausanne, Switzerland

3. Coordinators:

Korea		Switzerland	
Name (Position)	Affiliation	Name (Position)	Affiliation
Young-Ho Cho (Professor)	KAIST	Yves Leterrier (Professor)	EPFL

4. Participants:

Korea : 9 Persons
Switzerland : 9 Persons

5. Objective and Effectiveness:

Objective

The Symposium is intended to promote interdisciplinary research discussion and technical information exchange between Korea and Switzerland.

Effectiveness

The Symposium thus provided good opportunities to get together for discussing potential applications, new devices and enabling technologies for more innovative MEMS. More particularly, the state of the art and vision for the future in Korea and Switzerland for the development of new materials and novel processing technologies for more innovative MEMS were discussed. Special emphasis was given to low-stress polymers, functional ceramic and metallic materials, new manufacture and characterization techniques of structures at the micrometer scale, and novel devices.

6. Program:

Date	Speaker	Affiliation	Topic for Presentation
June 18, 19	Young-Ho Cho	KAIST	BioAnalogic Digital Nanolocomotion
	Sang Mo Shin	Micro Solution	Problem and Issues Related to the Packaging of Planar Integrated Optical Devices
	Jong Uk Bu	LG-ELITE	Material Issues on Commercialization of Microsystem in LG-ELITE
	Won Seok Chang	KIMM	3-D Micro Structure Fabrication by Using UV Laser
	Kwang Soo No	KAIST	Fabrication of PZT Thick Films on Silicon Substrates for Piezoelectric Actuator
	Jong Hyun Lee	K-JIST	Micromachined Latch-up Planar Actuator Driven by Thermoelastic Force
	Hak In Whang	KETI	A Millimeter-wave Image Sensor using Antenna-Coupled Vanadium Dioxide
	Seo Hyun Cho	SEC	New Thermal Inkjet Printhead Fabricated by MEMS

	Se Il Park	KRISS	Multilayer Thin-Film Thermal Converters Optimized by Temperature Profile Analysis
	Michel Despont	IBM Zurich Research Laboratory	The "Millipede" - More than 1000 Tips for Parallel and Dense Data Storage
	Philippe Renaud	IMS, EPFL	Thermally Activated Micromirrors : Application to Beam Steering and Gas Spectrometry
	Bert Willing	IR-Microsystems	High-End Infrared Detector Array Based on Pyroelectric Thin Film
	Jan-Anders Manson	LTC, EPFL	Novel Polymer-Based Materials for Low-Stress Packaging of MEMS
	Hubert Lorenz	Mimotec	Photofabrication of Ultra-Precise Micromolds
	Rolf Gottardt	IGA, EPFL	Shape Memory Alloys for Microengineering Systems
	Andre Perret	CSEM	CSEM Enabling Technology
	Nico De Rooij	IMS-UNI, Neuchatel	Microsystems for Diverse Applications using Recently Developed Microfabrication Technology
	Johann Michler	EMPA	MEMS - Materials Characterization and Reliability